

Title (en)
METHOD AND DEVICE FOR PRODUCING A STRUCTURED SURFACE

Title (de)
VERFAHREN ZUR ERZEUGUNG EINER STRUKTURIERTEN OBERFLÄCHE

Title (fr)
PROCÉDÉ ET DISPOSITIF DE FABRICATION D'UNE SURFACE STRUCTURÉE

Publication
EP 4303021 A3 20240313 (DE)

Application
EP 23210461 A 20180219

Priority
• DE 102017113035 A 20170613
• DE 102017113036 A 20170613
• EP 20155456 A 20180219
• EP 18157511 A 20180219

Abstract (en)
[origin: WO2018229164A1] The invention relates to a method for producing a decorative and textured surface having differing degrees of gloss, comprising the following steps: - feeding a workpiece (1.0) to a device for the application of a varnish, - applying, across the whole surface, a first liquid varnish layer (1.4) with course texturing wherein there is a thickness difference between thicker regions and thinner regions of at least 50 µm and particularly at least 100 µm, - and particularly digitally spraying droplets onto subsurfaces of the first varnish layer (1.4) on the workpiece (1.0), preferably using an at least partially transparent varnish, for the application of a second varnish layer (1.5) onto the first varnish layer (1.4), wherein said second varnish layer (1.5) has a different degree of gloss to the first varnish layer (1.4) after curing. The invention also relates to a device for carrying out the claimed method.

Abstract (de)
Es wird ein Verfahren zur Erzeugung einer dekorativen Oberfläche auf einem Werkstück (1) mit folgenden Schritten offenbart:- Zuführen (S10) des Werkstückes (1), das mit einer flüssigen Schicht (2) beschichtet ist, zu einer digitalen Druckstation;- Aufbringen (S12) eines Mittels, das dazu ausgebildet ist, elektromagnetische Strahlung zumindest teilweise zu absorbieren, zumindest auf eine Teilfläche der Oberfläche der flüssigen Schicht (2), oder welches in Kontakt mit der Oberfläche ein Reaktionsprodukt entstehen lässt, das derart beschaffen ist, dass es elektromagnetische Strahlung zumindest teilweise zu absorbieren vermag;- Bestahlen (S14) der Oberfläche der flüssigen Schicht (2) und des Mittels mit elektromagnetischer Strahlung.Ferner wird eine Vorrichtung (18) zur Durchführung dieses Verfahrens offenbart.

IPC 8 full level
B41F 23/08 (2006.01); **B05D 1/32** (2006.01); **B05D 1/36** (2006.01); **B05D 3/06** (2006.01); **B05D 3/12** (2006.01); **B05D 5/02** (2006.01); **B41F 23/04** (2006.01); **B41J 11/00** (2006.01); **B41M 3/06** (2006.01); **B41M 5/00** (2006.01); **B41M 7/00** (2006.01); **B44C 3/02** (2006.01); **B44C 5/04** (2006.01); **B44F 1/02** (2006.01); **B44F 9/02** (2006.01); **B05D 3/00** (2006.01); **B05D 3/04** (2006.01); **B41M 3/00** (2006.01); **B44F 11/04** (2006.01); **E04F 15/02** (2006.01)

CPC (source: CN EP US)
B05D 3/002 (2013.01 - CN US); **B05D 3/0486** (2013.01 - CN US); **B05D 3/067** (2013.01 - CN US); **B05D 3/12** (2013.01 - CN EP US); **B05D 5/02** (2013.01 - CN EP US); **B05D 7/584** (2013.01 - CN US); **B41F 23/08** (2013.01 - CN US); **B41J 2/2114** (2013.01 - US); **B41J 3/407** (2013.01 - US); **B41J 11/0015** (2013.01 - CN EP US); **B41J 11/002** (2013.01 - CN EP US); **B41M 3/06** (2013.01 - CN EP US); **B41M 5/0047** (2013.01 - CN US); **B41M 7/0027** (2013.01 - CN US); **B41M 7/0045** (2013.01 - CN EP US); **B41M 7/0054** (2013.01 - CN US); **B41M 7/0081** (2013.01 - CN EP US); **B41M 7/009** (2013.01 - US); **B44C 3/02** (2013.01 - CN EP US); **B44C 5/04** (2013.01 - CN EP); **B44F 1/02** (2013.01 - CN EP); **B44F 9/02** (2013.01 - CN); **B44F 11/04** (2013.01 - CN); **E04F 13/0873** (2013.01 - CN); **E04F 15/02** (2013.01 - CN); **E04F 15/107** (2013.01 - CN); **B05D 3/002** (2013.01 - EP); **B05D 3/0486** (2013.01 - EP); **B05D 3/067** (2013.01 - EP); **B05D 5/061** (2013.01 - US); **B41M 3/008** (2013.01 - EP); **B41M 5/0011** (2013.01 - EP); **B41M 5/0047** (2013.01 - EP); **B41M 7/0054** (2013.01 - EP); **B44C 5/04** (2013.01 - US); **B44F 1/02** (2013.01 - US); **B44F 9/02** (2013.01 - EP US); **B44F 11/04** (2013.01 - EP US); **E04F 13/0873** (2013.01 - US); **E04F 15/02** (2013.01 - EP); **E04F 15/107** (2013.01 - US)

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Designated contracting state (EPC)
AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

DOCDB simple family (publication)
EP 3415316 A1 20181219; **EP 3415316 B1 20200408**; CN 110267813 A 20190920; CN 110267813 B 20211022; CN 110290925 A 20190927; CN 110290925 B 20220415; CN 113212020 A 20210806; CN 113212020 B 20230808; DE 202018006283 U1 20200122; EP 3415319 A1 20181219; EP 3415319 B1 20200101; EP 3666525 A1 20200617; EP 3666525 B1 20231220; EP 3666525 C0 20231220; EP 4303021 A2 20240110; EP 4303021 A3 20240313; ES 2781801 T3 20200907; ES 2786985 T3 20201014; ES 2786985 T5 20240410; ES 2787041 T3 20201014; ES 2802801 T3 20210121; ES 2971866 T3 20240610; HU E050387 T2 20201130; PL 3415316 T3 20201005; PL 3415319 T3 20200713; PL 3666525 T3 20240429; PT 3415316 T 20200506; US 11141759 B2 20211012; US 11420229 B2 20220823; US 11511318 B2 20221129; US 11717850 B2 20230808; US 11717851 B2 20230808; US 11883843 B2 20240130; US 2020016627 A1 20200116; US 2020016629 A1 20200116; US 2020023662 A1 20200123; US 2020368777 A1 20201126; US 2021268542 A1 20210902; US 2021394232 A1 20211223; US 2022379343 A1 20221201; US 2022379344 A1 20221201; WO 2018229164 A1 20181220; WO 2018229167 A1 20181220; WO 2018229169 A1 20181220; WO 2018229170 A1 20181220

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HU E18157511 A 20180219; PL 18157511 T 20180219; PL 18168263 T 20180419; PL 20155456 T 20180219; PT 18157511 T 20180219;
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